



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: JAFARIAN-TEHRANI et al.

Examiner: UNKNOWN

Application No.: 10/816,211

Group No.: 1763

Filed: 3/31/2004

Confirmation No.: 7310

Title: METHODS AND ARRAY FOR CREATING A
MATHEMATICAL MODEL OF A PLASMA
PROCESSING SYSTEM

INFORMATION DISCLOSURE STATEMENT

US PATENT DOCUMENTS

| Examiner Initials | Cite No. | Document Number | Publication Date | Name of Patentee or Applicant | Reference to Related Case |
|----------------------|-------------|-----------------|------------------|----------------------------------|---------------------------|
| | | | | | |

OTHER DOCUMENTS

| Examiner Initials | Cite No. | Description | T |
|----------------------|-------------|--|---|
| Xur | 1 | STOUT et al., "Modeling Plasma Tools: Reactor and Feature Scales," pp. 1-6, http://www.google.com/search?q=cache:IPSVCEvzITsJ:cfdpplasma.trancetechno.com/vmic_2000.pdf+%22inductively+coupled+plasma%22+%22shower+head%22&hl=en&ie=UTF-8 | |
| | | | |
| | | | |

| | | | |
|-----------------------|----------------|--------------------|---------|
| Examiner Signature | <i>MPaslin</i> | Date Considered | 5-12-08 |
|-----------------------|----------------|--------------------|---------|